



PATENT
ATTY. DOCKET NO.: P67358US0 *CRW*

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

2822

In re Application of:

Hyung-Jun KIM

Group Art Unit: 2822

Serial No.: 10/015,757

Examiner: M. Lewis

Filed: December 17, 2001

For: SEMICONDUCTOR DEVICE CAPABLE OF PREVENTING CORROSION OF
METAL WIRES FROM CMP (CHEMICAL MECHANICAL POLISHING) PROCESS

TRANSMITTAL

Commissioner for Patents
P.O. Box 1450
Alexandria, Virginia 22313-1450

Sir:

Transmitted herewith is an Amendment Under Rule 1.111 for filing in the above-captioned patent application.

The fee has been calculated as shown below:

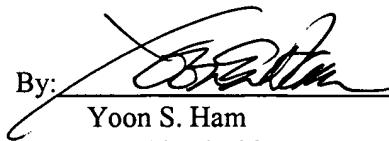
Claims Remaining After Amendment	Highest Number Previously Paid For	Present Extra	Small Entity Rate Addit. Fee	Other Than A Small Entity Rate Addit. Fee
Total 12 -	20 =	0	x 09 = \$	x 18 = \$
Indep. 03 -	03 =	0	x 42 = \$	x 84 = \$
<u>First Presentation of Multiple Dependent Claims</u>				
<u>Total Additional Fee</u>				
\$				

 A check in the amount of \$ is attached for:

XXXX If a Petition for Extension of Time is necessary and the Petition and/or the check is not enclosed, this will act as the Petition and applicant herewith petitions the Commissioner to extend the time for response and charge any fees necessary under 37 CFR 1.17 (a)(1)-(5) to Deposit Account No. 06-1358. The Commissioner is also authorized to charge payment of any other additional fees associated with this communication or credit any overpayment to Deposit Account No. 06-1358. A duplicate copy of this sheet is attached.

Respectfully submitted,
JACOBSON HOLMAN PLLC

By:


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AMENDMENT UNDER RULE 1.111

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P.O. Box 1450
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Sir:

In response to the Office Action (Paper No. 04292004) dated May 5, 2004, kindly
amend the above-identified patent application as set forth herein.